

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

re application of: Koch et al.

Attorney Docket No.: KLA1P050

Application No.: 10/052,307

Examiner: Not Yet Assigned

Filed: January 17, 2002

Group: Unknown

Title: SCANNING ELECTRON MICROSCOPE
ARCHITECTURE AND RELATED MATERIAL
HANDLING SYSTEM

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the
United States Postal Service as First Class Mail to: Commissioner for
Patents, Washington, DC 20231 on March 15, 2002.

Signed: 

Laura M. Dean

PRELIMINARY AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

Before examination of this application, please amend the above-identified patent
application as follows:

In the Specification:

Please **replace** the section entitled CROSS REFERENCE TO RELATED PATENT
APPLICATION with the following **amended** section:

This application claims the benefit of priority to U.S. Provisional Application
60/339,432, filed on December 11, 2001, entitled "Scanning Electron Microscope Architecture
And Related Material Handling System" by George R. Koch and Douglas Masnaghetti. This
application is also related to U.S. Patent Application number 60/339,487 filed on December 11,
2001 entitled "Transverse Magnetic Field Voltage Isolator," by James D. Olson and Jeffery
Coffer, the disclosure of which is incorporated herein by reference.